

<b>Notice of References Cited</b>	Application/Control No. 10/781,574	Applicant(s)/Patent Under Reexamination HUJANEN ET AL.	
	Examiner Kevin M. Bernatz	Art Unit 1773	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,270,572	08-2001	Kim et al.	117/93
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Klaus, J., Ferro, S., George, S., J. Elec. Soc., 147(3), 1175-1181, 2000 (Titled: "Atomic Layer Deposition of Tungsten Nitride Films Using Sequential Surface Reactions")
	V	Provisional Application 60/284,624
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.